



PATENT
2342-0111P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Kazuyuki TOYODA et al. Conf.: 6177

Application No.: 08/905,971 Group: 1763

Filed: August 5, 1997 Examiner: R. Zervigon

For: SUBSTRATE PROCESSING APPARATUS

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PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, DC 20231

July 20, 2001

Sir:

The following preliminary amendments and remarks are respectfully submitted, subsequent to the submission of Request For Continued Examination filed on July 17, 2001, in connection with the above-identified application.

IN THE CLAIMS

Please amend the claims as follows:

1. (Twice Amended) A substrate processing apparatus, comprising:

a substrate transfer section;

a plurality of modules, each of said plurality of modules being detachably attached to said substrate transfer section; and

a first substrate transfer device, provided in said substrate transfer section, for transferring substrates to said plurality of modules,

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